

# Thin Multilayer Bus

**Mauro Citterio,  
Valentino Liberali,  
Alberto Stabile**

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**INFN Milano**

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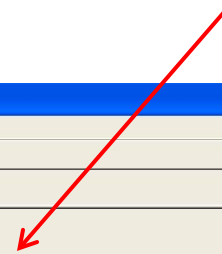
# 3-CHIP BUS

## Pixel Bus second generation:

- Layout details agreed with CERN
  - Various iterations ..... about 2 years
    - Signal layers modified
    - Opening between layers were optimized
  
- Production completed on November 2012
  - Layer by layer stack-up did not work out ...
    - Thin layers and registration problems
    - Layers separated into 3 groups ... Few pictures
  
  - Evaluation of the «few samples» received ... How we plan to procede

# 3-Chip BUS Stackup

No real layers !!  
inserted only for  
simulation



**Stackup Editor**

File Edit View Help

Basic | Dielectric Metal | Z0 Planning | Custom View

Layer Name	Type	Usage	Metal	Thickness um	Er	Bulk R ohm-m	T coef 1/C	Test Width um	Z0 ohm	Loss Curve	
1	TOP	Metal	Signal	Copper	1	<Auto>	1.724e-008	0.00393	5000	<Error>	View...
2	SOLDER_MASK	Dielectric	Substrate		1	4.5					
3	AVDD	Metal	Plane	Aluminum	25	<Auto>	2.688e-008	0.0038	5000	0.9	View...
4	Glue	Dielectric	Substrate		5	4.5					
5	Kapton	Dielectric	Substrate		12	3.5					
6	Glue	Dielectric	Substrate		5	4.5					
7	AGND	Metal	Plane	Aluminum	25	<Auto>	2.688e-008	0.0038	5000	1	View...
8	Glue	Dielectric	Substrate		50	4.5					
9	Kapton	Dielectric	Substrate		12	3.5					
10	Glue	Dielectric	Substrate		50	4.5					
11	INNER1	Metal	Signal	Copper	3	<Auto>	1.724e-008	0.00393	50	66.9	View...
12	Glue	Dielectric	Substrate		50	4.5					
13	Kapton	Dielectric	Substrate		12	3.5					
14	Glue	Dielectric	Substrate		50	4.5					
15	DVDD_CORE	Metal	Plane	Aluminum	25	<Auto>	2.688e-008	0.0038	5000	1	View...
16	Glue	Dielectric	Substrate		5	4.5					
17	Kapton	Dielectric	Substrate		12	3.5					
18	Glue	Dielectric	Substrate		5	4.5					
19	DGND_CORE	Metal	Plane	Aluminum	25	<Auto>	2.688e-008	0.0038	5000	1	View...
20	Glue	Dielectric	Substrate		50	4.5					
21	Kapton	Dielectric	Substrate		12	3.5					
22	Glue	Dielectric	Substrate		50	4.5					
23	INNER3	Metal	Signal	Copper	3	<Auto>	1.724e-008	0.00393	50	66.9	View...
24	Glue	Dielectric	Substrate		50	4.5					
25	Kapton	Dielectric	Substrate		12	3.5					
26	Glue	Dielectric	Substrate		50	4.5					
27	DVDD_MAT	Metal	Plane	Aluminum	25	<Auto>	2.688e-008	0.0038	5000	1	View...
28	Glue	Dielectric	Substrate		5	4.5					
29	Kapton	Dielectric	Substrate		12	3.5					
30	Glue	Dielectric	Substrate		5	4.5					
31	DGND_MAT	Metal	Plane	Aluminum	25	<Auto>	2.688e-008	0.0038	5000	0.5	View...
32	Glue	Dielectric	Substrate		5	4.5					
33	Kapton	Dielectric	Substrate		12	3.5					
34	BOTTOM	Metal	Plane	Copper	1	<Auto>	1.724e-008	0.00393	5000	0.7	View...

Z ~ 70 Ohm

Calculate Er for metal layers from surrounding dielectrics

Draw proportionally      Total thickness: 690 um

Use layer colors

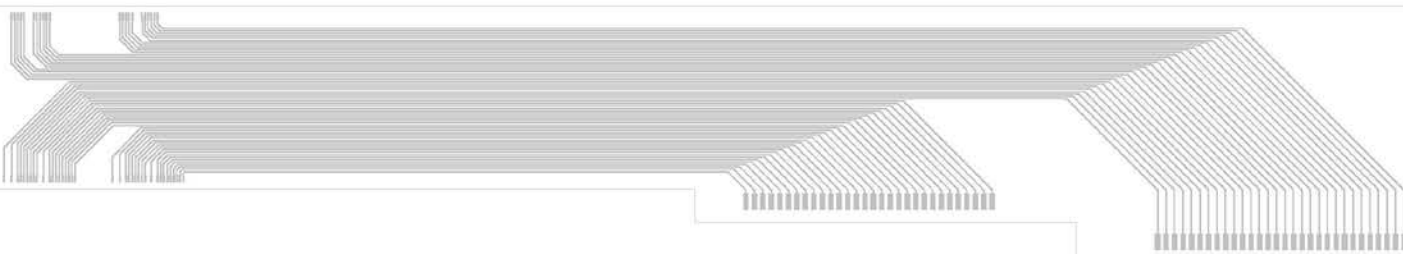
**No errors in stackup.**

Labels on the right of the diagram:  
 Z0 = <Error>  
 Z0 = 0.903 ohm  
 Z0 = 0.963 ohm  
 Z0 = 66.9 ohm  
 Z0 = 0.963 ohm  
 Z0 = 0.963 ohm  
 Z0 = 66.9 ohm  
 Z0 = 0.963 ohm  
 Z0 = 0.963 ohm  
 Z0 = 0.458 ohm  
 Z0 = 0.692 ohm

# Signal/Power layers



Two IC signals will share the same plane

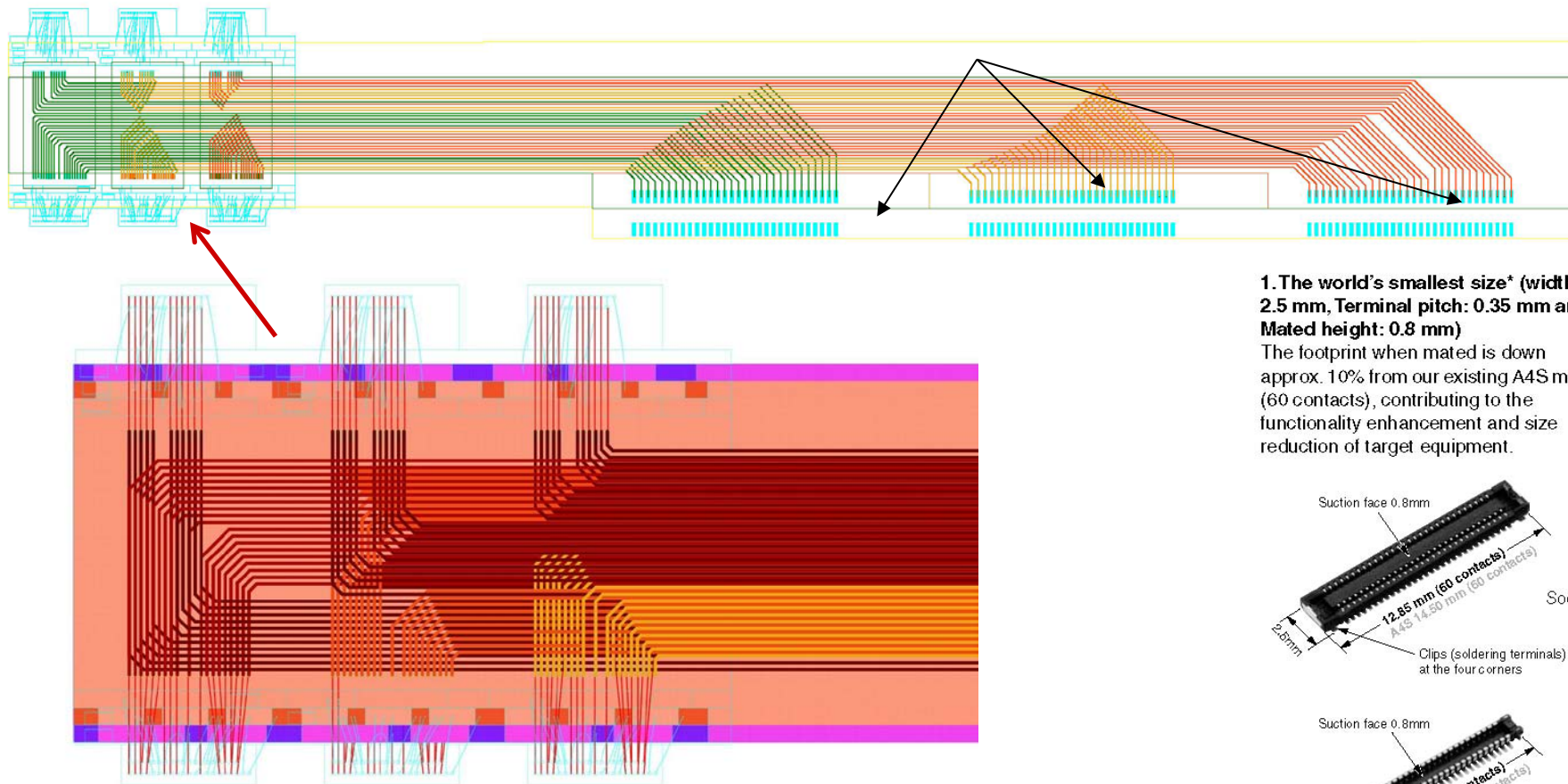


Simplified plane-cuts

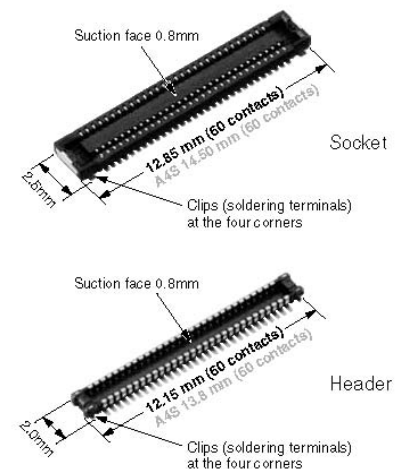
Panasonics high density connectors



# Overall view (using transparent layers)

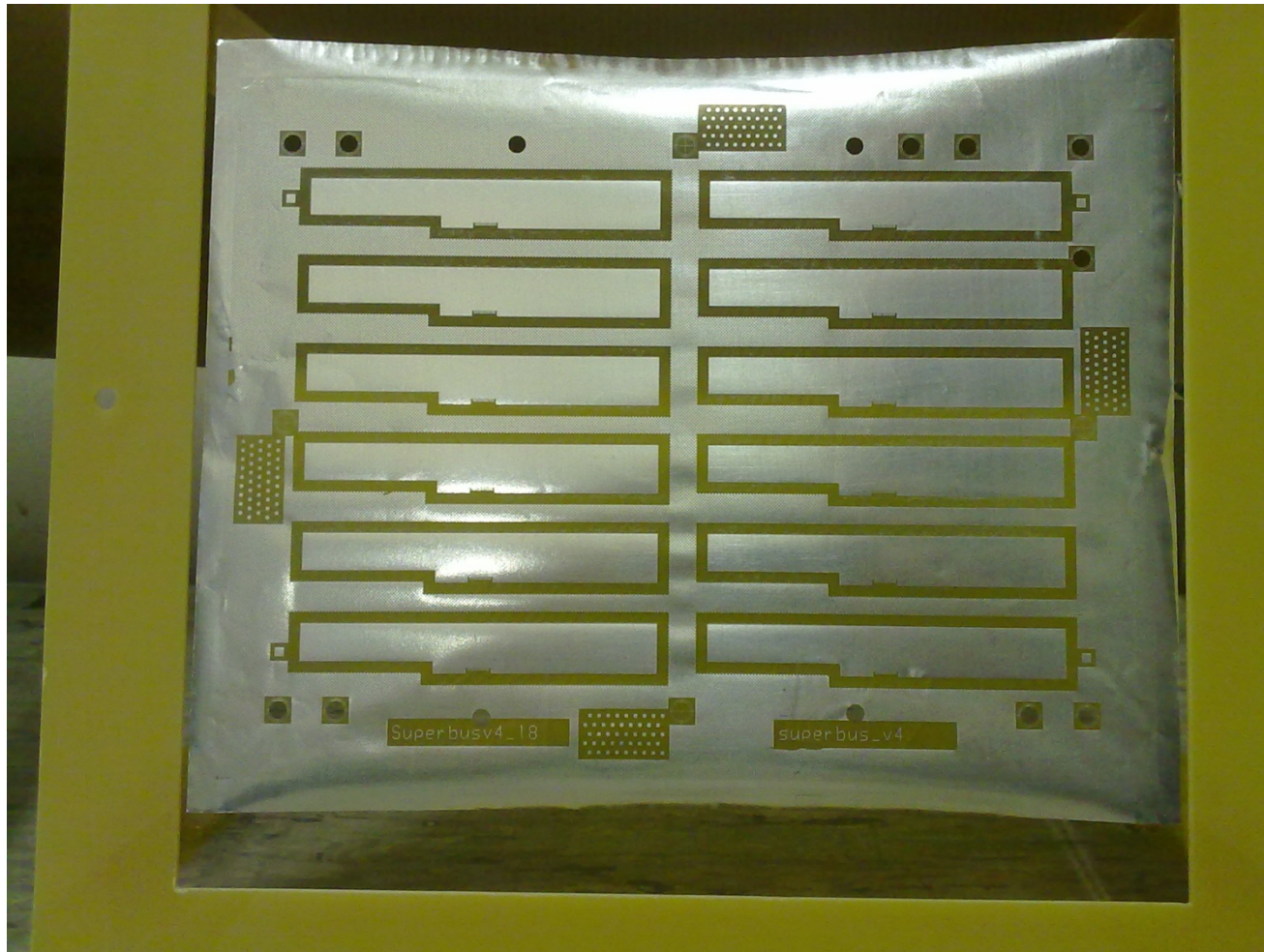


**1. The world's smallest size\* (width: 2.5 mm, Terminal pitch: 0.35 mm and Mated height: 0.8 mm)**  
 The footprint when mated is down approx. 10% from our existing A4S model (60 contacts), contributing to the functionality enhancement and size reduction of target equipment.



Layers were properly stacked ... cut-outs per each layer were optimized to preserve “bonding topology”

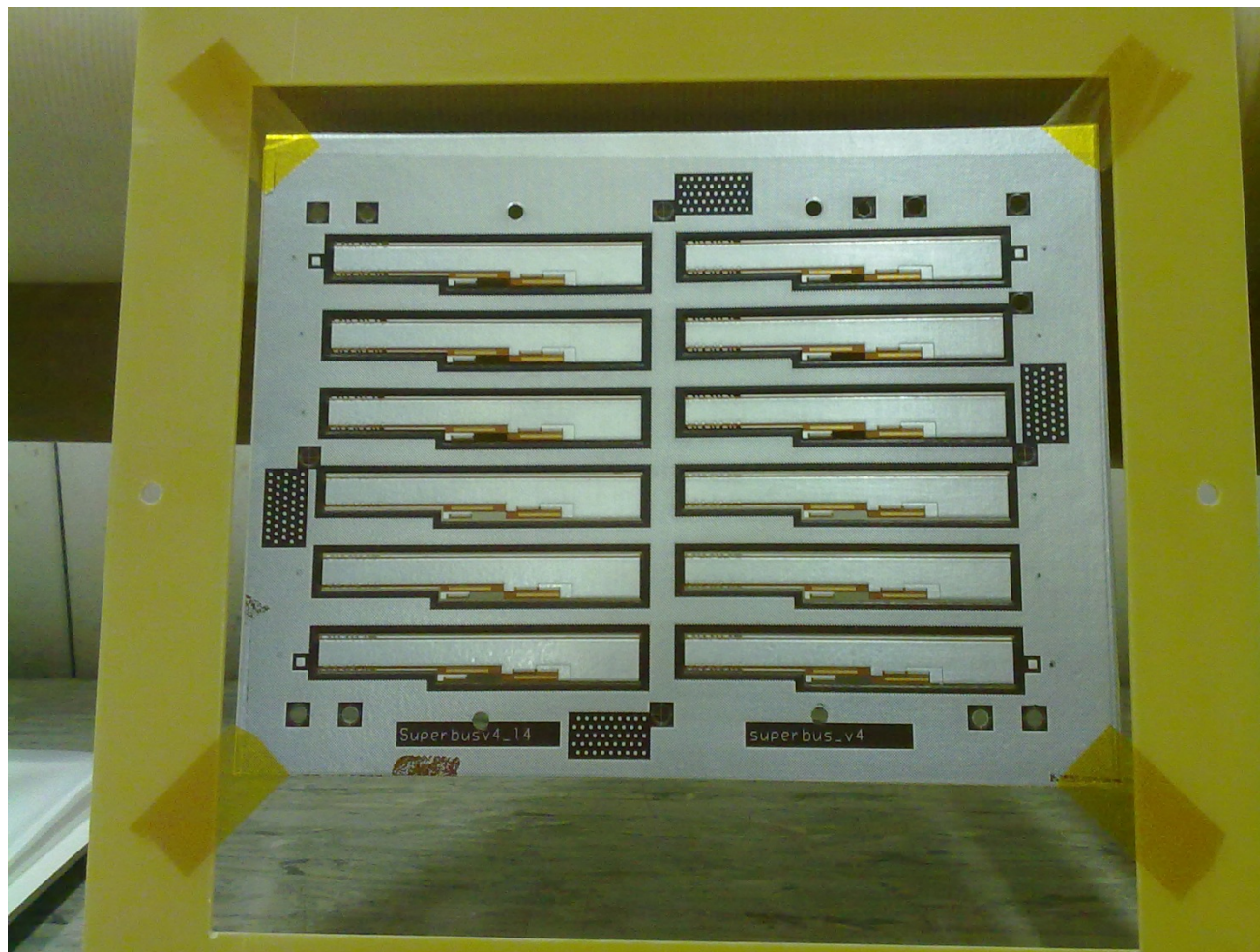
- Bus produced using a Frame that contains 16 structures
- In the picture “dgnd\_core.bottom” is shown (1 layer)
  - Extremely flexible layer but difficult to align properly



2<sup>nd</sup> sandwich made of 4 layers: 3 planes, 1 signal layer

→ In the picture are shown: “dvdd\_core.inner6”, “**signal2.inner5**”,  
 “dvdd\_mat.inner3” and “dgnd\_mat.inner4”

→ Yield ~ 100 %

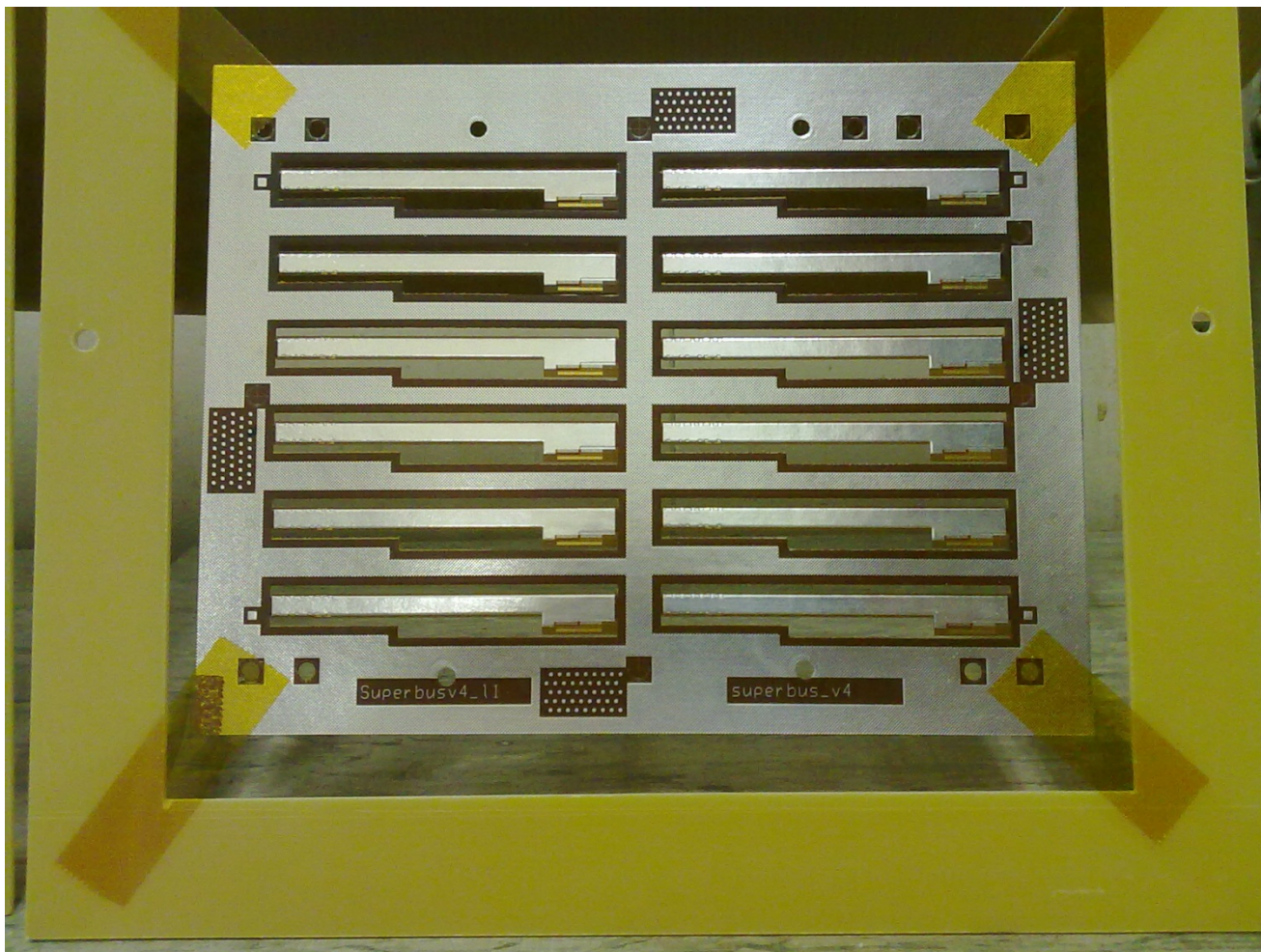




2<sup>nd</sup> sandwich made of 3 layers: 2 planes, 1 signal layer

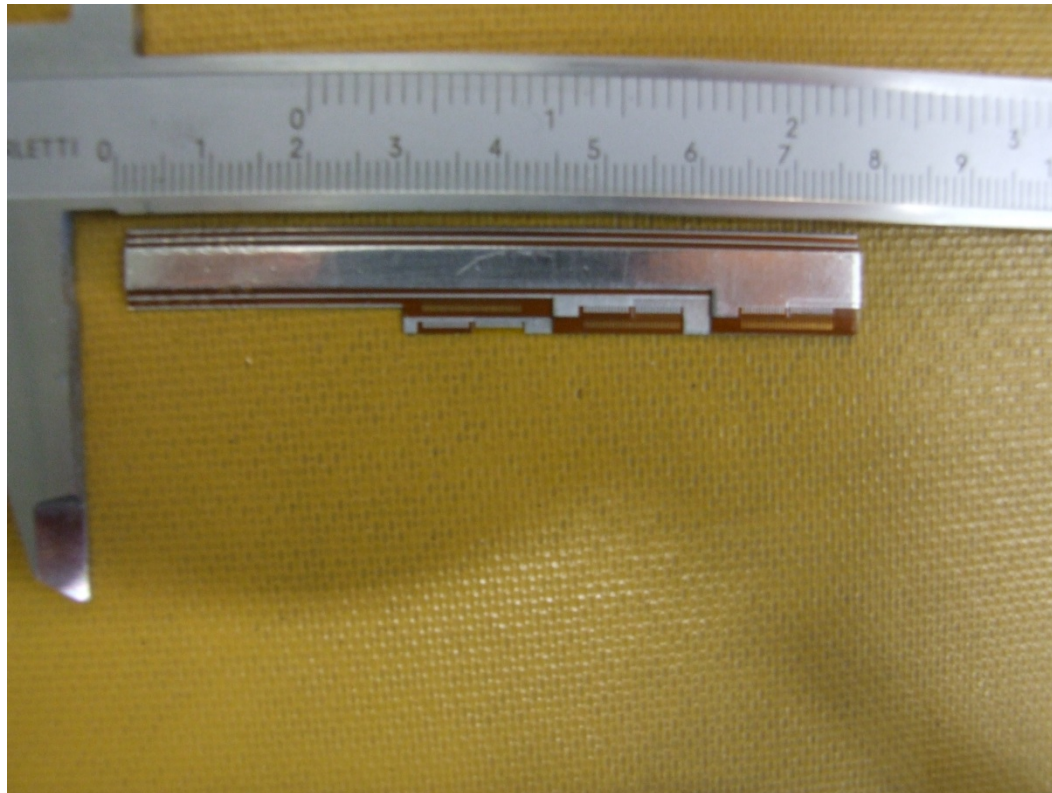
→ In the picture are shown: “avdd.top”, “agnd.inner1” and “**signal1.inner2**”

→ Yield ~ 100 %



# Final Object

- To obtain the final bus the 3 sandwiches are “glued” together after alignment and preparation
- Yield is low, < 50 % : **2 pieces in Milan**, 2 at CERN plus 3-4 pieces to be evaluated carefully

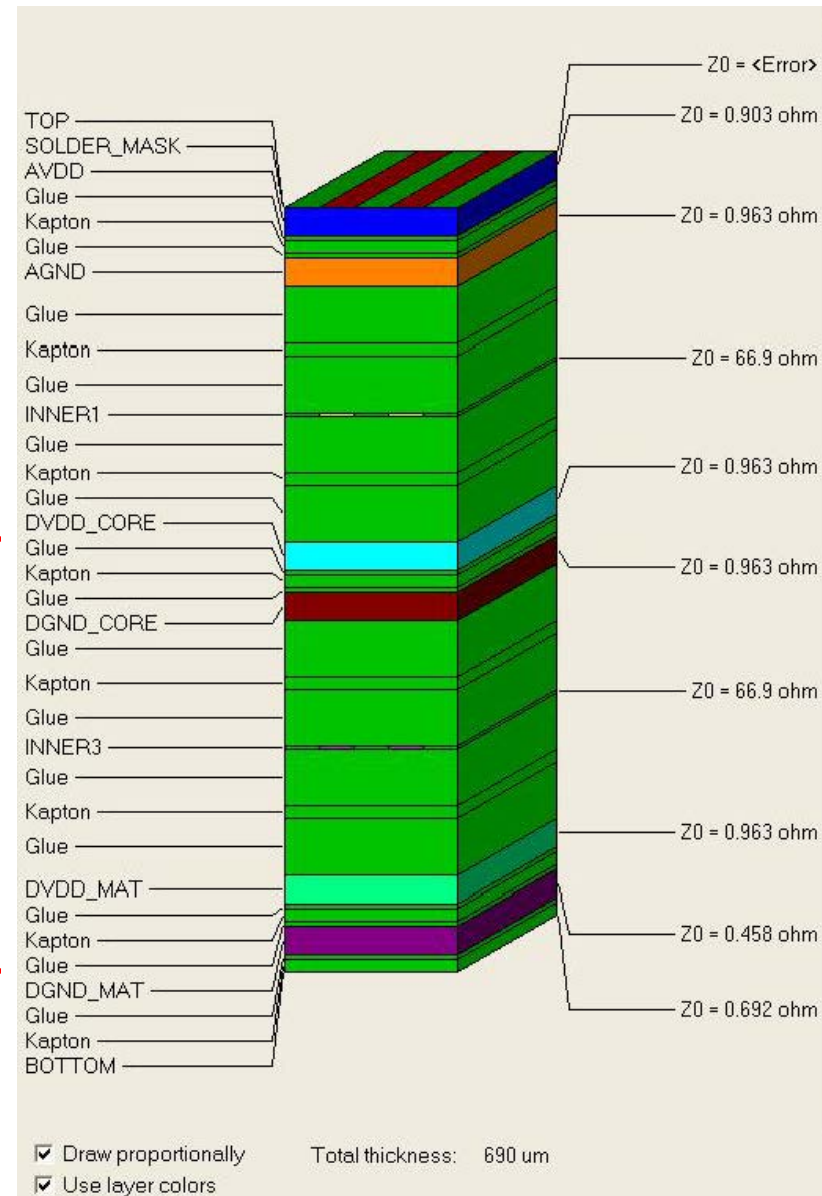


# Consideration and X0 reduction

What could be **probably** done:

- No. of power planes: 2 .... max 3
  - *One plane subdivided in Analogue and Digital sub-planes? Not clear. No "sophisticated" pattern capability if treated as planes*
- However two planes allow strip-lines design (better for crosstalk)
- Signal trace pitch could be reduced to  $\sim 50$  micron to have only one signal layer for the signal.
  - *Aluminum lines possible !*

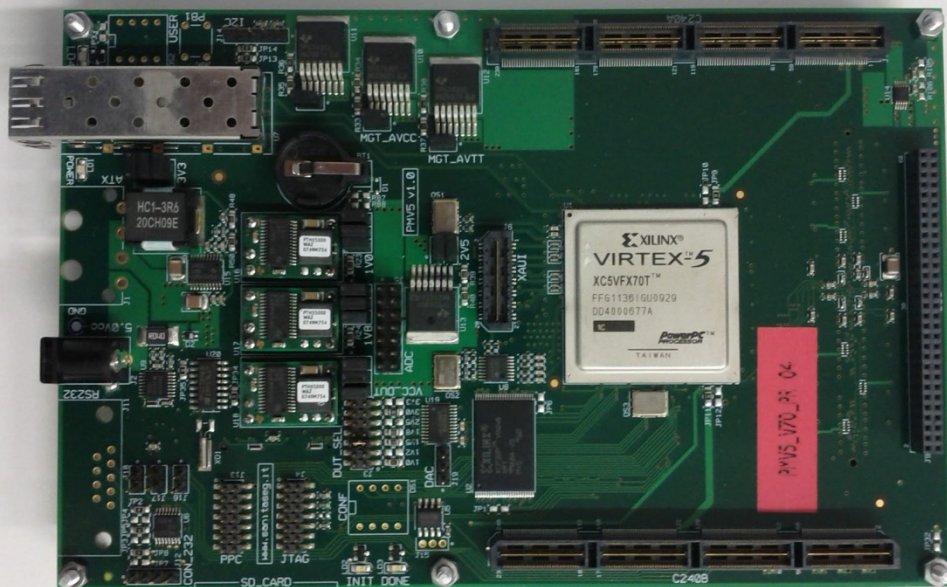
Thickness, after optimization, could be  $\sim 350$   $\mu\text{m}$



# BUS Characterization Setup

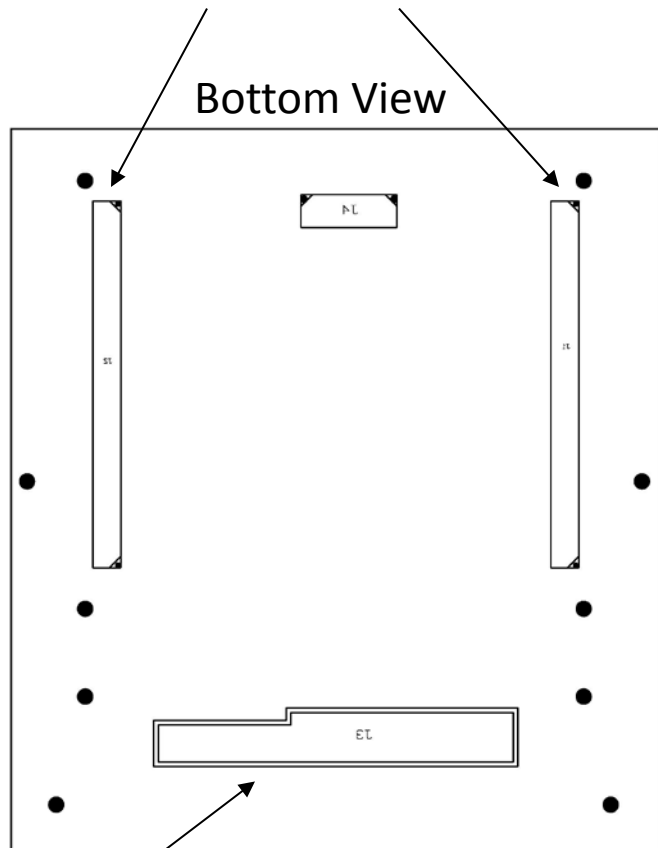
Multipurpose mother/daughter combination of boards developed together with SANITAS S.r.l (Milano):

- Based on a Virtex 5 “controller board” (showed in picture)
- Multiple daughter boards can be plugged in to customize testing (using connectors on the right side of board)
- Daughter board for BUS testing is in production at TVR
- Firmware is almost complete
  - To inject signals/patterns (via Pattern generator or via FPGA)
  - To measure Bit Error Rate (at various frequency, w/wo jitter, w/wo skew)
  - The system can grow to emulate full data link (stacking up more daughter boards)



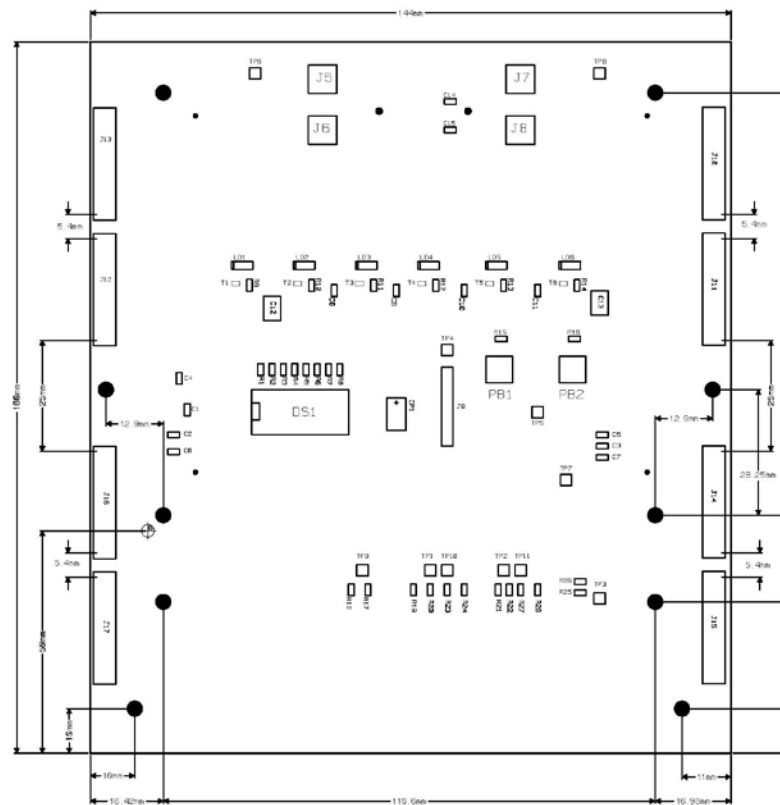
# Daughter board for the BUS

High density connectors matching motherboard



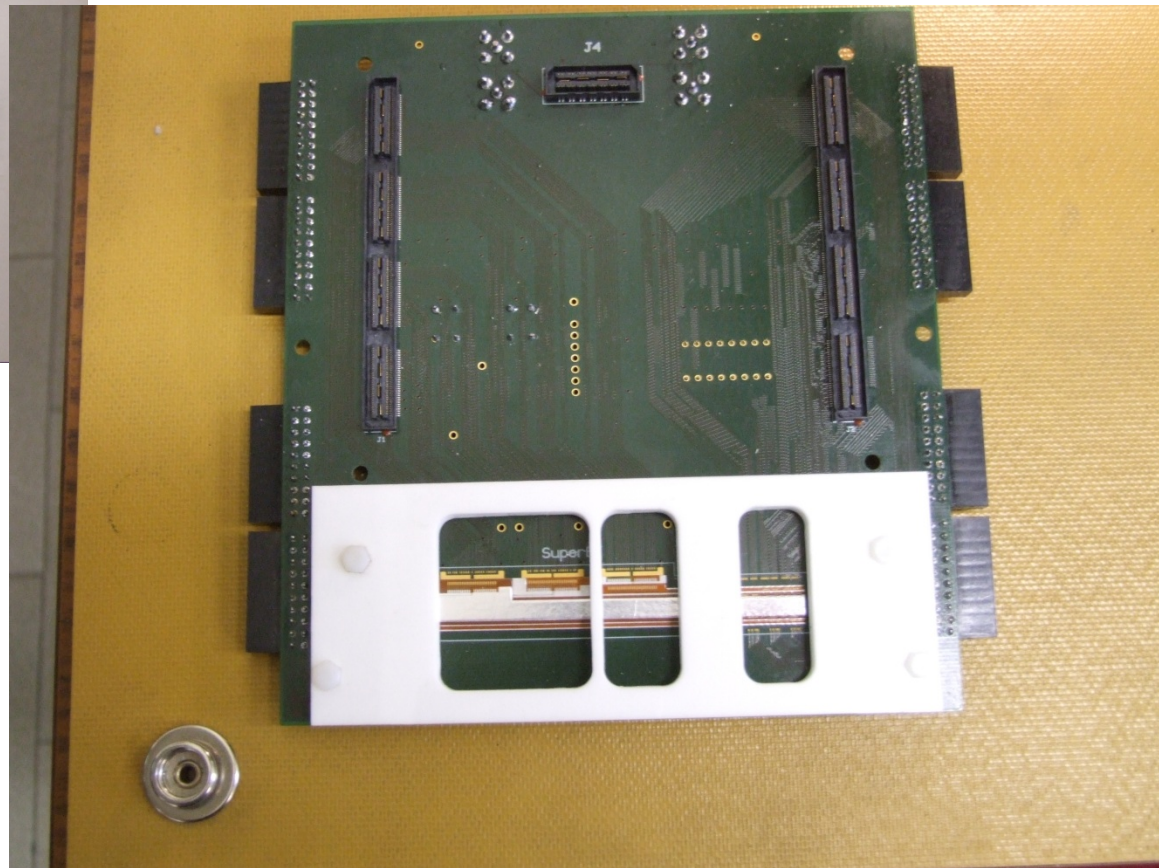
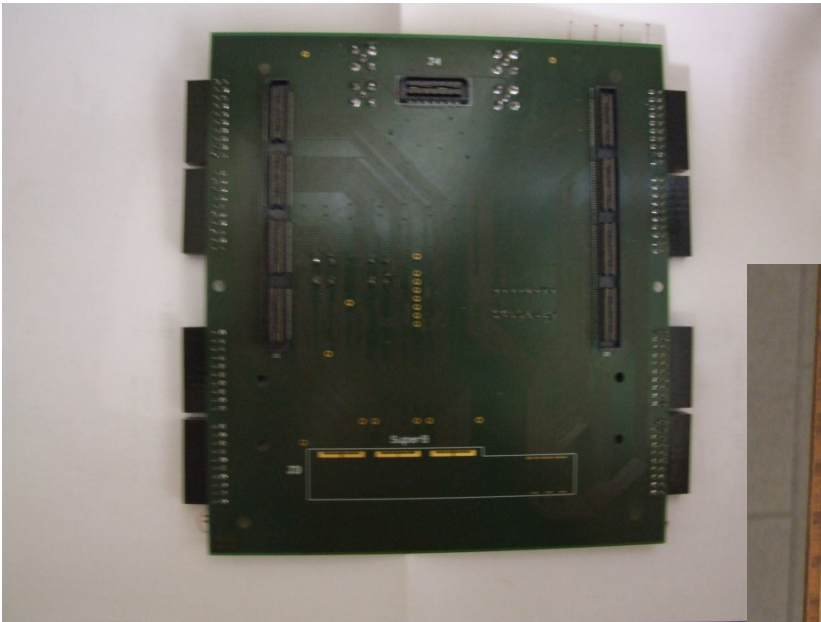
3-Chip Fanout

Top View



IN/OUT lines matched for impedance and “paired” in length for each chip ( $\Delta L \sim \text{cm}$ )

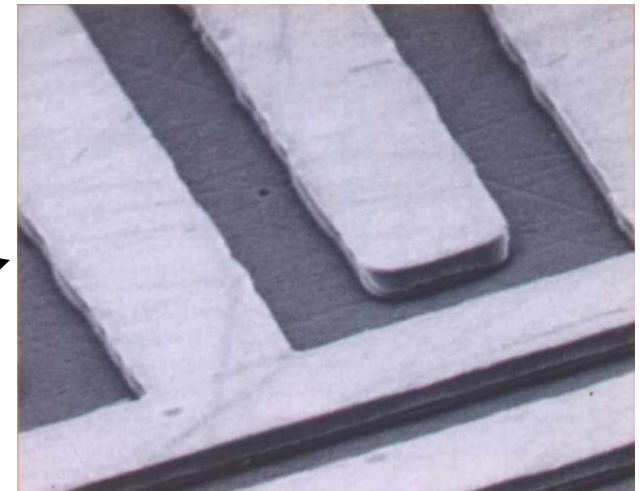
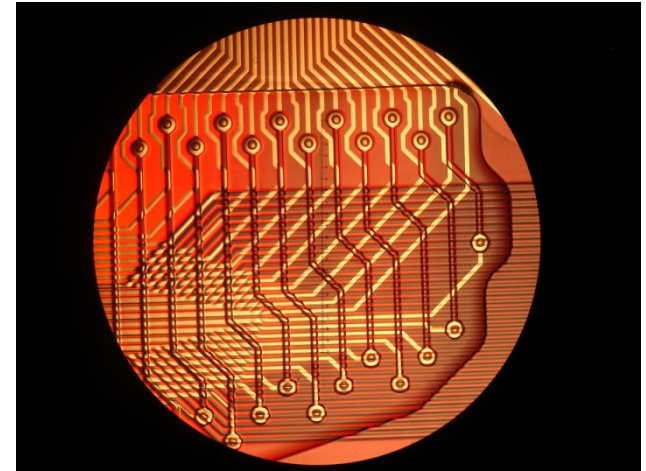
# Daughter Card



# Future Solution

What is needed:

- Ultra high resolution single and multilayer circuitry on flexible materials → **YES**
- Aluminum instead of copper → **MAYBE**
- Using high resolution photolithography, precision electroforming, and thin film deposition, high resolution flex circuits and electrode array plates can be made ... up to **~ 2x2 cm**
- Conductor widths and spaces of 5 microns can be achieved .... But on what maximum dimensions? **~ 2cm**
- Specialized companies ..... Are they interested in prototyping? **YES, initial cost to be understood**



MAGNIFICATION: 1.21 KX  
 5 Micron Conductors  
 5 Micron Spaces

# Conclusions

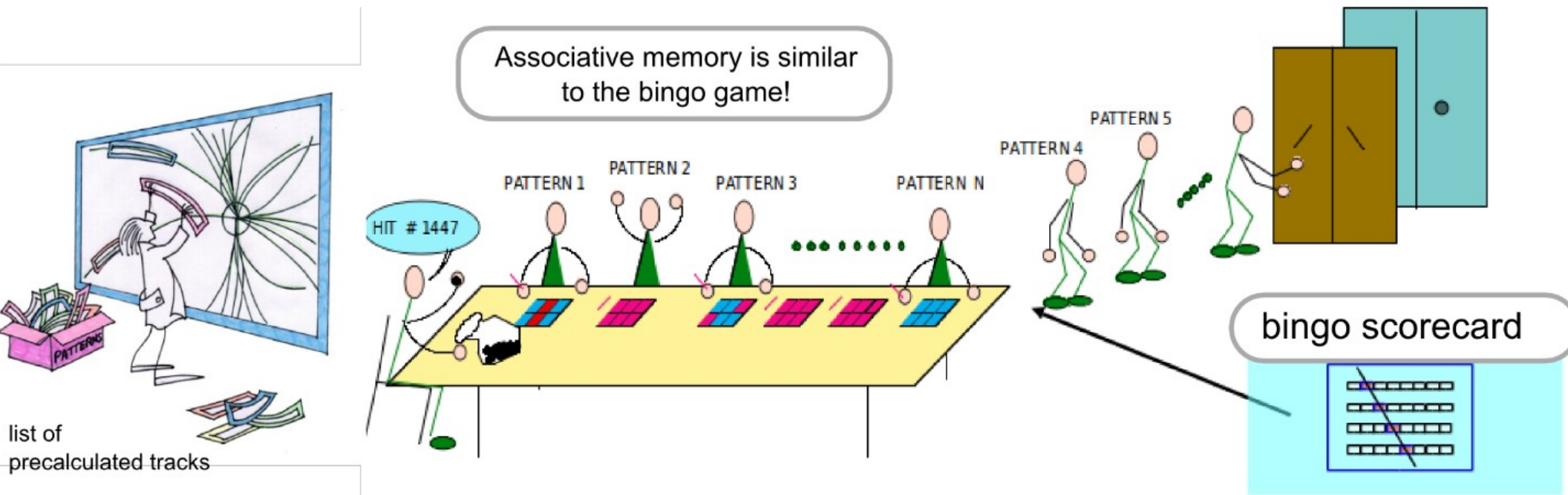
- CERN has undoubtedly a proven capability in producing low mass, multilayer, flexible circuits
  - However 3-4 layers it's the limit
    - 2-3 planes (~50  $\mu\text{m}$ ), 1 signal (10  $\mu\text{m}$ )
    - 50/50  $\mu\text{m}$  pitch in Al possible
  - We still need to verify how close the BUS matches our design specs
    - We should have asked for the individual sandwiches
- Special commercial applications are requesting ultra-thin flexible circuits
  - At least one company is willingly to talk to us and it is also interested in producing prototype
  - Power planes: “strange beasts” for these technologies, again low power is welcome



# FTK on going effort

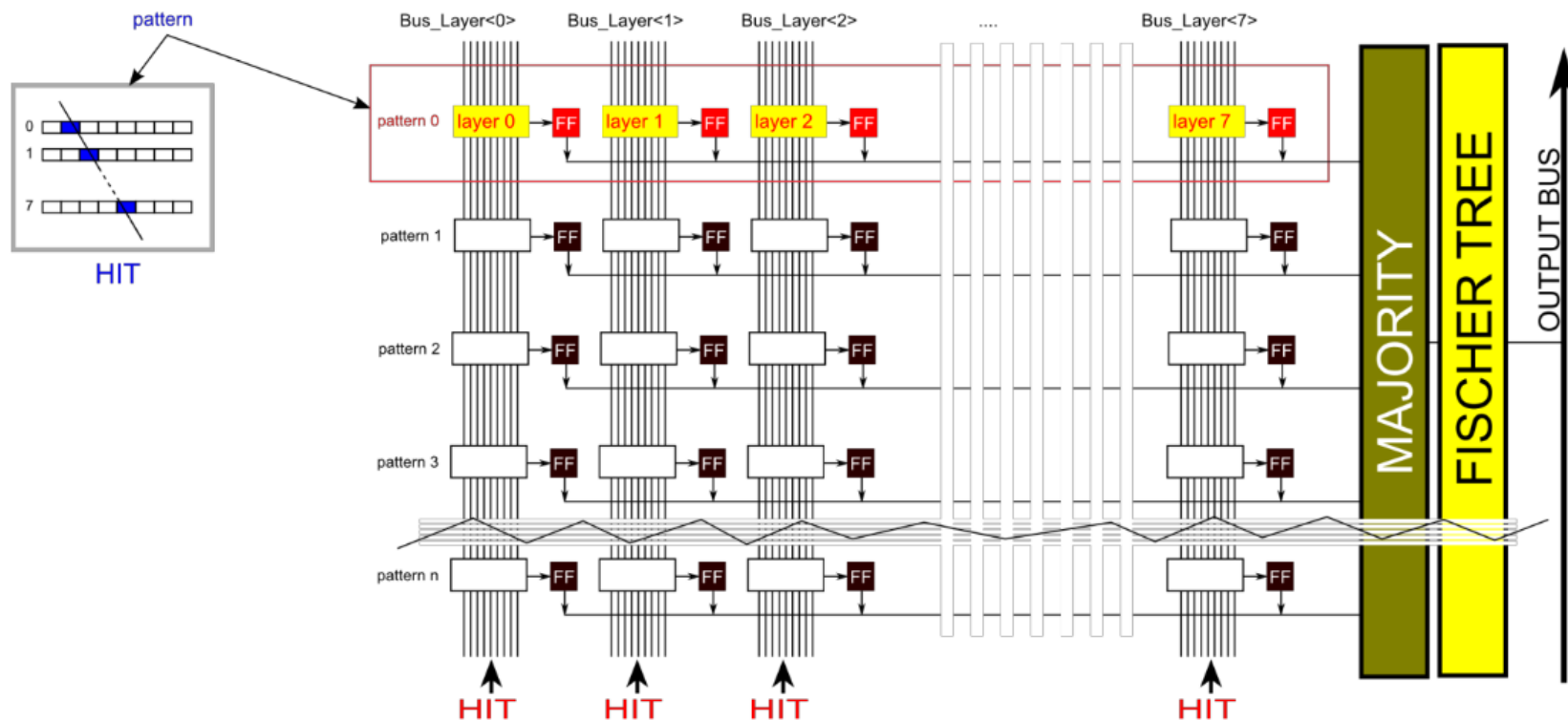
# AMchip theoretical principle

- ▶ **Associative Memory chip: AMchip**
  - ▶ Dedicated VLSI device - maximum parallelism
  - ▶ Each pattern with private comparator
  - ▶ Track search during detector readout



# Amchip

- ▶ Main aim: **pattern recognition of Super Strips!**
  - ▶ Count the number of matching layers (from 6 to 8 layers)
  - ▶ **Bit map** of matching patterns
  - ▶ **Variable resolution “pattern-by-pattern” and “layer-by-layer”**



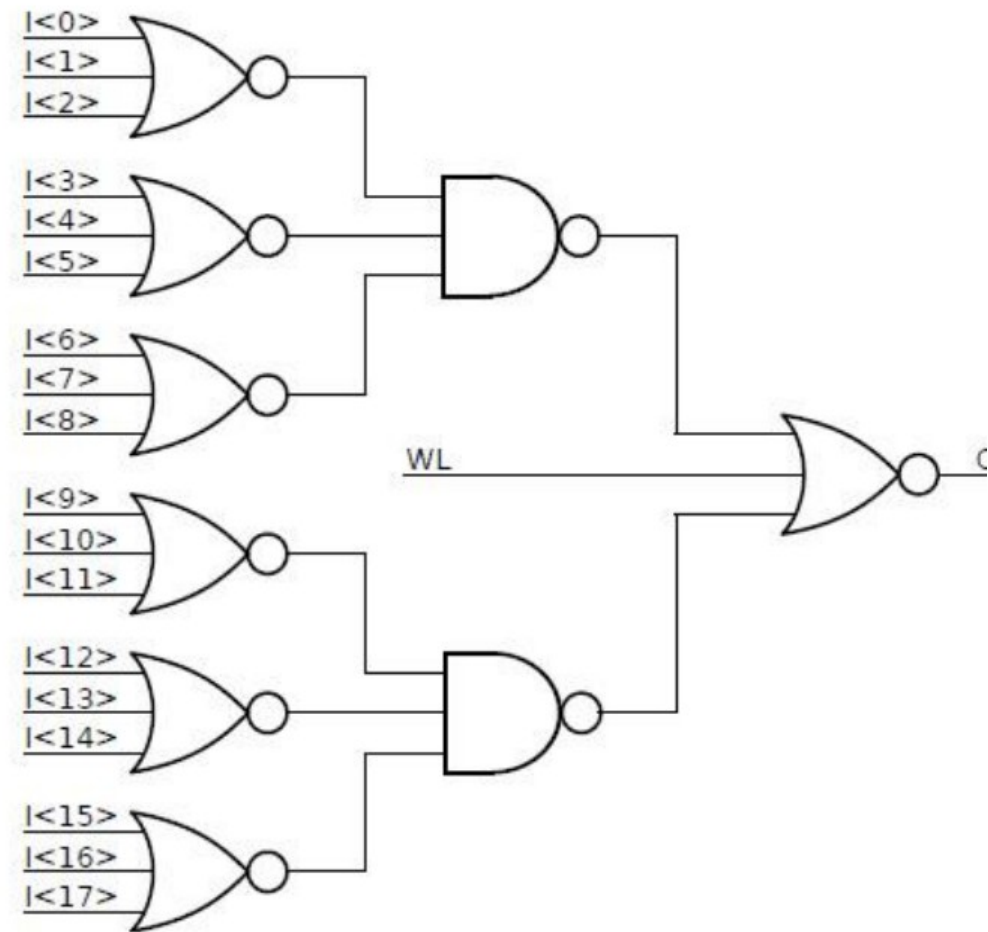
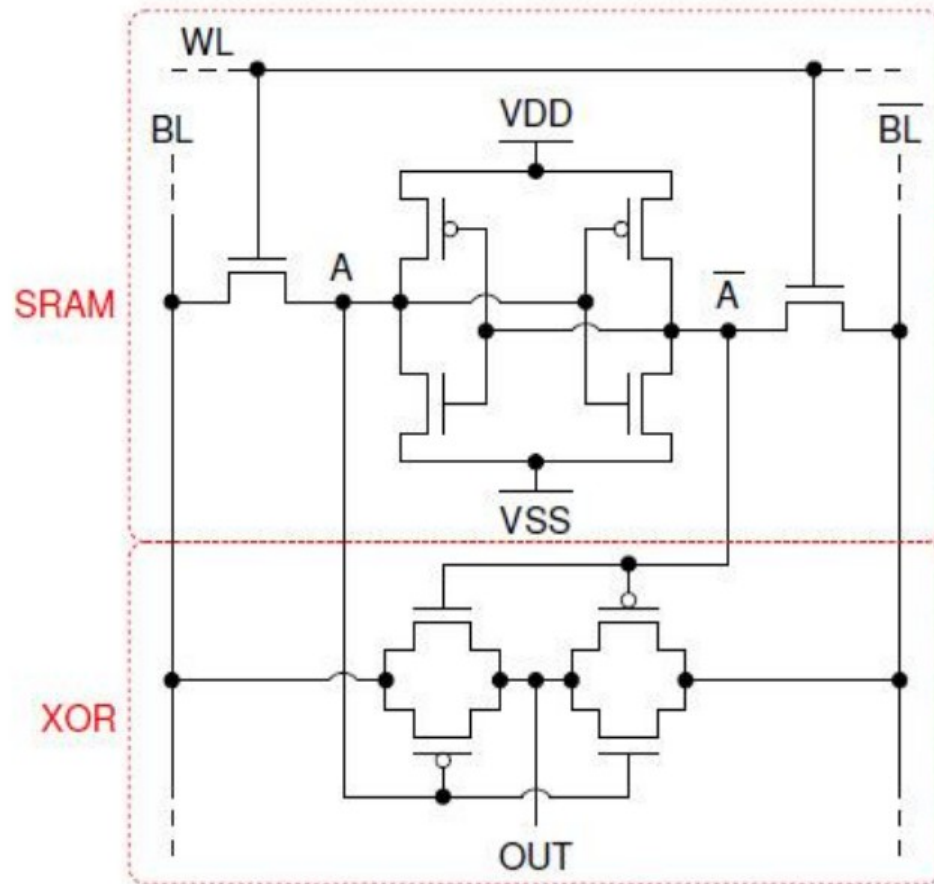


# Mini@sic goals & description

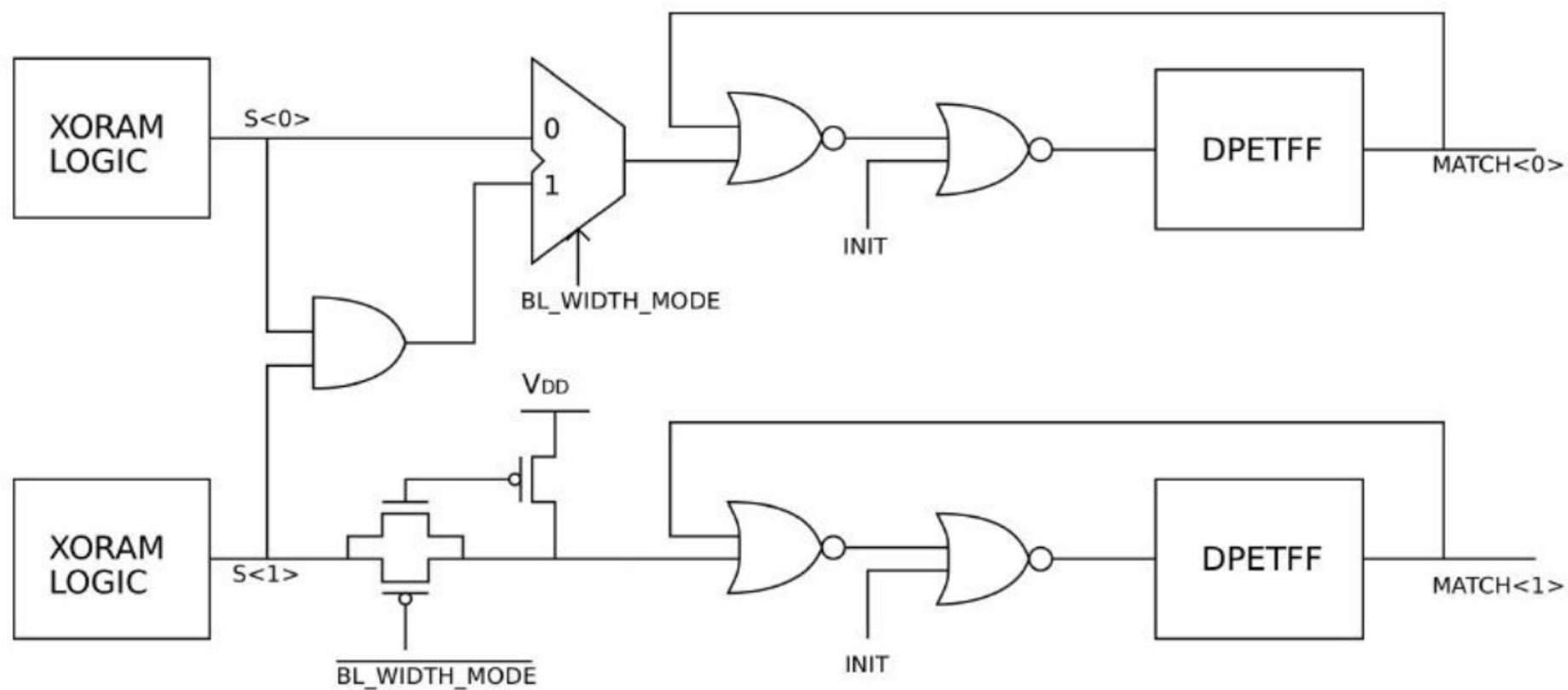
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- ▶ Test chip between the AMchip04 and AMchip05
    - ▶ New features
      - ▶ Hits and roads are **serialized and de-serialized** inside the chip core
        - **Silicon Creation® SerDes** IP blocks have been used for this purpose
        - Silicon Creation® LVDS pad has been used to bring inside the chip an external LVDS clock
          - The LVDS pad needs of a Band Gap Voltage Reference (always by Silicon Creation ®)
      - ▶ Two different type of Associative Memory (AM) cells have been used
        - **A new XOR+RAM cell** has been used with the aim to reduce silicon area and power consumption
      - ▶ **A more programmable Bit Line (BL) width mode**
        - With the XOR+RAM is possible to select how much is large the hit buses: 30 bit or 15 bit
      - ▶ **Built-In Self Test (BIST)** used to stimulate the AM banks at maximum working frequency through JTAG commands
        - PRBS generator to stimulate the banks
-

# The new “XOR+RAM = XORAM”



# XORAM architecture



# Submission

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